



**PATENT**  
**MIC04 P-106**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Examiner : George A. Goudreau  
Group : 1763  
Applicant : Imad Mahawili, PhD  
Serial No. : 09/488,309  
Filed : January 20, 2000  
For : REACTOR WITH REMOTE PLASMA SYSTEM AND  
METHOD OF PROCESSING A SEMICONDUCTOR  
SUBSTRATE

Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

ELECTION

In response to the Restriction Requirement mailed January 11, 2002, having a thirty-day period of response ending February, 10, 2002, Applicant wishes to elect the following invention:

Applicant provisionally elects the species which includes ionizing nitrogen.

REMARKS

The Examiner requires an election of a single disclosed species and identifies seven (7) species; namely a fluorine based gas; N<sub>2</sub> gas; H<sub>2</sub> gas; NH<sub>3</sub>-silane gasses; silane gas; O<sub>2</sub> gas; and O<sub>2</sub>-silane gasses. As noted above, Applicant provisionally elects the species which includes nitrogen gas. The claims readable on the elected species include Claims 1-44, 47, 53, and 55-75.

The Examiner acknowledges that Claims 1-44, 53, and 55-77 are currently generic to the disclosed species. Should any one of these generic claims be allowed, Applicant will request that the non-elected species be brought back in to the case and considered along with the allowed generic claim or claims provided that they are dependent on or otherwise incorporate all the limitations of the allowed generic claim or claims.

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